

## RESPONSE TO OFFICE ACTION

Serial No. 10/805,890

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IN THE UNITED STATES  
PATENT AND TRADEMARK OFFICE

## PATENT APPLICATION

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FEB 13 2006

Applicant: Nallan et al.

Case: 7017C1/ETCH/METAL-NVM/JB

Serial No.: 10/805,890

Filed: March 22, 2004

Examiner: Tran, Binh X

Group Art Unit: 1765

Title: METHOD OF PLASMA ETCHING OF HIGH-K DIELECTRIC MATERIALS WITH  
HIGH SELECTIVITY TO UNDERLYING LAYERSMail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450.

## CERTIFICATE OF FACSIMILE TRANSMISSION UNDER 37 C.F.R. §1.8

I hereby certify that this correspondence is being transmitted by facsimile  
under 37 C.F.R. §1.8 on February 13, 2006 and is addressed to Mail Stop  
Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA  
22313-1450, Facsimile No: (571) 273-8300.

2-13-06

Date

Signature

SIR:

RESPONSE TO OFFICE ACTION DATED NOVEMBER 23, 2005

In response to the Office Action dated November 23, 2005, having a statutory period for response set to expire on February 23, 2006, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782 for the Terminal Disclaimer fee under 37 C.F.R. §1.20(d). Although the Applicants believe that no other fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782 for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

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